

Cascade Summit™

The Benchmark for On-wafer Test and Characterization

eVue™ digital imaging system

- Easy probe set-up and navigation
- Simultaneous display of up to three cameras and optical magnifications
- Widest field of view for easy navigation
- Highest optical magnification for precise probe alignment
- Live motion frame rate to avoid damage to probes or wafer
- Internal focus allows fast Z-profiles to maintain contact over temperature

Versatile microscope mounts

- High-stability or large-area
- Tilt back allows easy access to probes
- Manual, motorized or programmable

Connection panels

- Coax, triaxial, and pin jack feed-troughs available
- Limit cable strain and motion for measurement stability
- Instrument stays connected to at back of panel
- Probe connection made at front of panel
- Simple to rearrange cabling when needed

PureLine™ technology

- Enhanced EMI shielding
- Lowest spectral noise floor and system AC noise
- Ideal for low level and 1/f measurements

AttoGuard®

- Extends instrument guard to completely surround wafer
- Makes the station invisible to the instrument
- Extremely low capacitance and leakage characteristics
- Fast settling times

Rollout stage

- Full wafer access for safe and easy loading
- Maintains chuck integrity without contaminating layers
- Easy access to calibration substrates on auxiliary chucks

MicroChamber®

- EMI shielding for low noise measurements
- Environmentally sealed for moisture-free, low-temperature measurements
- Low volume for the fastest purge
- Light tight to eliminate the need for a dark box

MicroChamber access door

- Hardware interlock to protect user from hazardous chuck bias voltage
- Full width for easy access to wafers and cal substrates

Platen lift

- Easy contact and separate function for probe cards and positioners
- Available micrometer adjustment to set probe card contact

Compact footprint

- Suitable for bench top use to preserve lab space
- vibration isolation table

Velox™ probe station control software

- Intuitive GUI for efficient system utilization by novice and expert users
- Software joystick for precise, sub-micron positioning
- Improved sub-die navigation with CellView
- Easy integration with instrument, testers, and test and measurement software for fast data collection

Powerful automation tools for data collection

- Automatic wafer alignment
- Auto XYZ and theta correction for sub-micron stepping
- Automatic die size measurement tool

Ergonomic accessory mount

- Keyboard and microscope controls easily accessed
- Maintains an orderly workspace on platen and benchtop

TopHat™

- Maintains MicroChamber integrity
- Allows full access to positioners and microscope at any temperature
- Allows adjustments without exposing chamber to external environment
- Maintains chuck temperature, thermal equilibrium, and mechanical stability during probe adjustments

Modular chucks

- FemtoGuard® triaxial and coax versions available
- High-performance thermal and economical non-thermal options
- Wide range of temperature options from -60 °C to 300 °C and higher
- 200mm and 150mm versions

Auxiliary chucks

- Two integrated mounts for calibration substrates
- Thermally isolated to prevent load drift over temperature
- Contact height can be set independently from wafer
- Microwave absorber options available

Chuck vacuum control

- Independent zones for various wafer sizes, die and shards
- Separate controls for auxiliary chucks

Manual mode stage control

- Intuitive manual controls
- Wafer can be removed in the event of a power outage



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